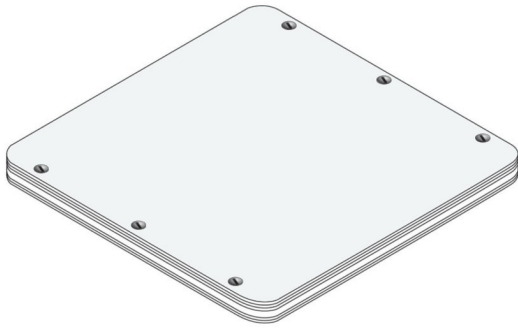


# Ossila Fabrication System

for Organic Light Emitting Diodes (OLEDs), Organic Photovoltaics (OPVs) and a variety of other research devices.

# Ossila

Accelerate • Innovate • Electrify

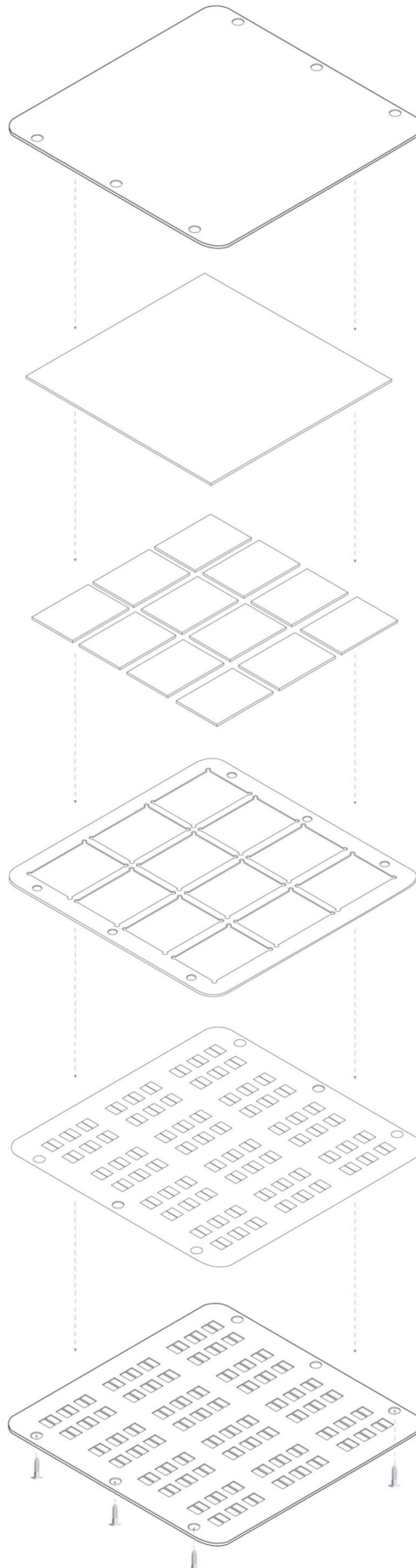


Ossila's OFET source/drain evaporation stack

We provide OFET shadow masks, substrates and mechanical support that fit together to produce a simple-to-use fabrication system for top/bottom contact OFETs. Our evaporation stack makes it easy to evaporate source drain contacts onto our standard size substrates (20 mm x 15 mm).

To make high quality OFETs it is crucial for the shadow mask to be in close contact with the substrate. This can be difficult in many evaporators which hold substrates upside down. However, the Ossila stack provides close contact regardless of what angle it is held at. Two mechanical supports hold the OFET mask flat and the substrates in place. A magnetic sheet then pulls the thin bars which define the channel between the source and drain into close contact with the substrate. A lid bolts everything in place for a mechanically stable system, suitable for use in a variety of evaporation systems.

The stack will accommodate up to 12 substrates, each of which has six OFETs with standard source/drain contacts if 2 mm x 4 mm. Interchangeable masks allow for different mask design.



Ossila's Lid

The lid holds the substrates and magnetic sheet in position.



Ossila's Magnetic Sheet

The magnetic sheet pulls the shadow mask into contact with the substrate, even upside down.



Ossila's Substrates

Up to twelve substrates per mask (sold separately).



Ossila's Upper Support

Holds and aligns the substrates in position above the shadow mask



Ossila's Shadow Mask

Interchangeable shadow masks: either **linear** or **interdigitated**. There are six OFETs per substrate.



Ossila's Lower Support

The lower support provides mechanical support to the delicate shadow mask.